Laser Microfabrication for Accelerator Applications

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Laser microfabrication allows high precision ablation of materials at sub-mm scale. When laser pulse length is shorter than about 10 picoseconds the heat affected zone is minimized and ablation occurs without melting. Work-pieces processed in this fashion exhibit less structural damage and are expected to have a higher damage thresholds. In this paper we will review several case studies of laser-microfabricated components for accelerator and x-ray applications. Ablated materials include diamond, quartz, tungsten, copper, YAG:Ce and silicon.



Femtosecond lens cutter development



Argonne Cathode Test Stand: emission markers

Cathode with pre-defined emitters

- Emitters created by fs-laser ablation, geometry enhancement of 3

Collaboration with J. Shao, AWA, Argonne



- Large emittance due to strong transverse field of the pin-in-well configuration, low imaging properties expected



w/o collimator



w/ Φ1 mm collimator



Measurement



Pepper pot for emittance measurement - Tungsten





Apodization for CO2 laser mirror (COPPER)

Reflection (x,y)

Collaboration with M. Polyanskiy ATF, Brookhaven

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Apodization for CO2 laser mirror (COPPER)



Power coupler for CO2 laser mirror (COPPER)



Power coupler for CO2 laser mirror (COPPER)



Compression gratings for CO2 laser (COPPER)



Standard echelette Ablation optimized

For high power operation: Higher efficiency No sharp features

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Other copper components for THz













A store the

Moth Eye Broadband THz Windows ~ 100um scale



- Materials: silicon, quartz
- Broadband impedance matching via periodic arrangement of sub-λ features (1D - grooves and 2D needles)
- ~100um depth / ~100um periodicity ~ 1 THz design





